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MULTISCALE PROCESS MONITORING IN NANOMANUFACTURING



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Multiscale process
monitoring in
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Case Study: Nano-wafer in CMP process



Condition: New. Publisher/Verlag: LAP Lambert Academic Publishing | Case Study: Nano-wafer in CMP process | The detection of the end of polishing during the chemical mechanical planarization (CMP) process is a critical task in semiconductor manufacturing. Even the research in CMP has grown and developed, one cannot predict the End point detection in order to avoid over or underpolishing wafer. The disadvantages of offline approach in endpoint detection have incited the researchers to discover an efficient substitute. In this Master...

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